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Sensors and Actuators A 63 (1997) 258

SENSORS AND ACTUATORS A PHYSICAL

Author Index of Volume A63

Ansari, F., 177

Bao, M., 1, 19, 217
Beerschwinger, U., 229
Benoit, D., 251
Bergveld, P., 97, 163
Buchanan, R.C., 33

Cattan, E., 91
Chahoud, M., 141
Chao, L.-P., 105
Chen, H., 19, 217
Chen, K.-T., 105
Cheng, Y.C., 147, 223
Choi, W.K., 243
Chong, C.W., 243
Cunningham, M.J., 125, 135

Damjanovic, D., 153
Delaunay, G., 7
Devos, F., 205

Estève, D., 183

Fan, S., 169
Fenniri, H., 7
Fisher, N.E., 27, 119
Fox, G.R., 153

Gaub, H.E., 47
Grattan, K.T.V., 85, 113, 197

Hardcastle, B.M., 61
Hofmann, U.G., 47
Hök, B., 69
Hu, Y.L., 85
Huang, M.Q., 223

Jaber, B., 91
Jackson, D.A., 27, 119
Jakšić, A., 129
Jenkins, D.F.L., 125, 135

Khalid, M.A.Hj., 125

Lai, P.T., 147, 223
Lawes, R.A., 61
Lee, M.H., 169
Li, B., 147
Li, G.Q., 223
Li, X., 1, 217
Li, Z., 209
Linde, H., 251
Liu, B.Y., 147
Liu, G., 169
Liu, L., 209
Ludden, B.P., 15

Meggitt, B.T., 85
Meijerink, M.G.H., 163
Moineau, A., 7

Ni, Y., 205
Ning, Y.N., 113

Olthuis, W., 97, 163
Owicki, J.C., 47

Palmer, A.W., 85, 113
Parak, W.J., 47
Pechstein, T., 191
Pedersen, M., 97, 163
Pejović, M., 129

Reid, D.J.C., 15
Remiens, D., 91, 135
Reuben, R.L., 229
Ristić, G., 129
Robertson, P.A., 15
Romare, D., 197
Rossi, C., 183
Rule, J., 15

Sabry-Rizk, M., 197
Scheid, E., 183
Schlachetzki, A., 141
Shen, S., 1, 19, 217
Smith, L., 69
Sorge, S., 191
Strandman, C., 69
Sundeen, J.E., 33
Syms, R.R.A., 61

Tenerz, L., 69
Thierry, B., 91
Thong, J.T.L., 243
Tronc, P., 91

Velu, G., 135

Wajid, A., 41
Wang, C., 205
Wehmann, H.-H., 141
Whiting, C., 251
Woolsey, G.A., 27, 119

Yang, S.J., 229
Yuan, L., 177

Zeng, S.H., 223
Zhang, W., 113
Zhang, Z.Y., 85
Zheng, X.R., 147
Zhu, H., 19
Zou, Q., 209

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Sensors and Actuators A 63 (1997) 259–261

SENSORS AND ACTUATORS A PHYSICAL

Subject Index of Volume A63

Accelerometers
a piezoresistive accelerometer with a novel vertical beam structure, 19
Acoustic detection
Bragg grating in a two-mode optical fibre for sensing applications, 15
Adaptive filtering
evaluation of different adaptive filtering techniques applied to white-light interferometric sensor systems, 197
Anisotropic etching
a production process of silicon sensor elements for a fibre-optic pressure sensor, 69
anisotropic-etching simulation of InP and Si, 141

Beams
finite-element modelling and simulation on frequency characteristics of the silicon beam resonator attached to an E-type round diaphragm for measuring the concentrated force, 169
Bulk-glass current sensors
tuning a bulk-glass optical current sensor by controlling conditions external to its reflecting surfaces, 27
Faraday current sensors and the significance of subtended angles, 119
Bulk micromachining
bulk micromachined silicon comb-drive electrostatic actuators with diode isolation, 61

Capacitance
study on linearization of silicon capacitive pressure sensors, 1
Capacitive sensors
an IC-compatible polyimide pressure sensor with capacitive readout, 163
Ceramics
characterization of ferroelectric and piezoelectric properties of lead titanate thin films deposited on Si by sputtering, 91
Cermet films
electrical properties of nickel–zirconia cermet films for temperature- and flow-sensor applications, 33
Comb-drive electrostatic actuators
bulk micromachined silicon comb-drive electrostatic actuators with diode isolation, 61
Composite films
electrical properties of nickel–zirconia cermet films for temperature- and flow-sensor applications, 33
Condenser microphones
theoretical and experimental studies of single-chip-processed miniature silicon condenser microphone with corrugated diaphragm, 209
Conduction percolation
electrical properties of nickel–zirconia cermet films for temperature- and flow-sensor applications, 33
Corrugated diaphragms
theoretical and experimental studies of single-chip-processed miniature silicon condenser microphone with corrugated diaphragm, 209
CVD oxide
PMOS dosimetric transistors with two-layer gate oxide, 129

Decay-time thermometry
ruby-based decay-time thermometry: effect of probe size on extended measurement range (77–800 K), 85
Deconvolution
the use of some iterative deconvolution algorithms to improve the spatial resolution of a flat magnetic sensor, 7
Dielectric membranes
theoretical and experimental study of silicon micromachined microheater with dielectric stacked membranes, 183
Differential sensors
an IC-compatible polyimide pressure sensor with capacitive readout, 163
Diode isolation
bulk micromachined silicon comb-drive electrostatic actuators with diode isolation, 61

Electrostatic actuation
cantilever vibration control by electrostatic actuation for magnetic force microscopy, 125
Etch characteristics
etch characteristics of various materials in ethanolamine etchants, 251
Etching parameters
TMAH etching of silicon and the interaction of etching parameters, 243
Etching simulation
anisotropic-etching simulation of InP and Si, 141
Ethanolamine etchants
etch characteristics of various materials in ethanolamine etchants, 251
E-type round diaphragms
finite-element modelling and simulation on frequency characteristics of the silicon beam resonator attached to an E-type round diaphragm for measuring the concentrated force, 169

Fading
PMOS dosimetric transistors with two-layer gate oxide, 129
Faraday current sensors
Faraday current sensors and the significance of subtended angles, 119
Ferroelectric properties
characterization of ferroelectric and piezoelectric properties of lead titanate thin films deposited on Si by sputtering, 91
Fiber optics
white-light interferometric fiber-optic distributed strain-sensing system, 177
Fiber-optic thermometers
ruby-based decay-time thermometry: effect of probe size on extended measurement range (77–800 K), 85
Fibre Bragg gratings
Bragg grating in a two-mode optical fibre for sensing applications, 15
Finite-element method
finite-element modelling and simulation on frequency characteristics of the silicon beam resonator attached to an E-type round diaphragm for measuring the concentrated force, 169

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Flow sensors
electrical properties of nickel–zirconia cermet films for temperature- and flow-sensor applications, 33
Fluorescence lifetime
ruby-based decay-time thermometry: effect of probe size on extended measurement range (77–800 K), 85
Force
finite-element modelling and simulation on frequency characteristics of the silicon beam resonator attached to an E-type round diaphragm for measuring the concentrated force, 169
Force sensitivity evaluation
shape optimal design and force sensitivity evaluation of six-axis force sensors, 105
Force sensors
shape optimal design and force sensitivity evaluation of six-axis force sensors, 105
Friction
frictional study of micromotor bearings, 229

Gas chromatography
fully integrated thermal conductivity sensor for gas chromatography without dead volume, 191
Gas sensors
fully integrated thermal conductivity sensor for gas chromatography without dead volume, 191
Guide-wire fibre-optic pressure sensors
a production process of silicon sensor elements for a fibre-optic pressure sensor, 69

Humidity sensitivity
photo-, thermal and humidity sensitivity characteristics of $Sr_{1-x}La_xTiO_3$ film on SiO_2/Si substrate, 223

IC-compatible sensors
a silicon condenser microphone with polyimide diaphragm and backplate, 97
Indium phosphide
anisotropic-etching simulation of InP and Si, 141
Integrated sensors
an integrated PVDF ultrasonic sensor with improved sensitivity using polyimide, 147
an IC-compatible polyimide pressure sensor with capacitive readout, 163
Interface traps
PMOS dosimetric transistors with two-layer gate oxide, 129
Iterative algorithms
the use of some iterative deconvolution algorithms to improve the spatial resolution of a flat magnetic sensor, 7

Lateral acceleration
a piezoresistive accelerometer with a novel vertical beam structure, 19
Lateral resolution
lateral resolution of light-addressable potentiometric sensors: an experimental and theoretical investigation, 47
Lead titanate
characterization of ferroelectric and piezoelectric properties of lead titanate thin films deposited on Si by sputtering, 91
Light-addressable potentiometric sensors (LAPSs)
lateral resolution of light-addressable potentiometric sensors: an experimental and theoretical investigation, 47
Light-pulse detectors
a cumulative differential light-pulse detector using source-coupled MOS current switches, 205
Linearity
study on linearization of silicon capacitive pressure sensors, 1

Magnetic force microscopy
cantilever vibration control by electrostatic actuation for magnetic force microscopy, 125
Maskless etching
a novel micromachining technology for multilevel structures of silicon, 217
Microactuators
the use of sputtered ZnO piezoelectric thin films as broad-band microactuators, 135
Microheaters
theoretical and experimental study of silicon micromachined microheater with dielectric stacked membranes, 183
Micromachining
a piezoresistive accelerometer with a novel vertical beam structure, 19
a novel micromachining technology for multilevel structures of silicon, 217
Micromotor bearings
frictional study of micromotor bearings, 229
Microsensors
finite-element modelling and simulation on frequency characteristics of the silicon beam resonator attached to an E-type round diaphragm for measuring the concentrated force, 169
MOS current switches
a cumulative differential light-pulse detector using source-coupled MOS current switches, 205

Optical current-measurement systems
analysis of the effect of vibration-induced noise in different fibre leads used in an optical current-measurement system, 113
Optical current sensors
Faraday current sensors and the significance of subtended angles, 119
Optical fibres
analysis of the effect of vibration-induced noise in different fibre leads used in an optical current-measurement system, 113
Optical phase modulator
electrical characterization of sputter-deposited ZnO coatings on optical fibers, 153
Optimal design
shape optimal design and force sensitivity evaluation of six-axis force sensors, 105
Oxide trapped charge
PMOS dosimetric transistors with two-layer gate oxide, 129

Photosensitivity
photo-, thermal and humidity sensitivity characteristics of $Sr_{1-x}La_xTiO_3$ film on SiO_2/Si substrate, 223
Piezoelectric optical-fiber coatings
electrical characterization of sputter-deposited ZnO coatings on optical fibers, 153
Piezoelectric properties
characterization of ferroelectric and piezoelectric properties of lead titanate thin films deposited on Si by sputtering, 91
Piezoelectric thin films
the use of sputtered ZnO piezoelectric thin films as broad-band microactuators, 135
electrical characterization of sputter-deposited ZnO coatings on optical fibers, 153
{100} Planes
a production process of silicon sensor elements for a fibre-optic pressure sensor, 69
PMOS dosimeters
PMOS dosimetric transistors with two-layer gate oxide, 129
Polyimide
a silicon condenser microphone with polyimide diaphragm and backplate, 97
an integrated PVDF ultrasonic sensor with improved sensitivity using polyimide, 147

an IC-compatible polyimide pressure sensor with capacitive readout, 163
Potassium hydroxide
a production process of silicon sensor elements for a fibre-optic pressure sensor, 69
Pressure sensors
study on linearization of silicon capacitive pressure sensors, 1
an IC-compatible polyimide pressure sensor with capacitive readout, 163

Quartz-crystal microbalances
on the accuracy of the quartz-crystal microbalance (QCM) in thin-film depositions, 41

Radial resonance
electrical characterization of sputter-deposited ZnO coatings on optical fibers, 153
Reactive sputtering
electrical characterization of sputter-deposited ZnO coatings on optical fibers, 153
Restoration of sensor images
the use of some iterative deconvolution algorithms to improve the spatial resolution of a flat magnetic sensor, 7
Ruby
ruby-based decay-time thermometry: effect of probe size on extended measurement range (77–800 K), 85

Sensitivity
PMOS dosimetric transistors with two-layer gate oxide, 129
Silicon
study on linearization of silicon capacitive pressure sensors, 1
bulk micromachined silicon comb-drive electrostatic actuators with diode isolation, 61
characterization of ferroelectric and piezoelectric properties of lead titanate thin films deposited on Si by sputtering, 91
anisotropic-etching simulation of InP and Si, 141
TMAH etching of silicon and the interaction of etching parameters, 243
Silicon condenser microphones
a silicon condenser microphone with polyimide diaphragm and backplate, 97
Silicon etch
a novel micromachining technology for multilevel structures of silicon, 217
Single-chip fabrication
theoretical and experimental studies of single-chip-processed miniature silicon condenser microphone with corrugated diaphragm, 209
$Sr_{1-x}La_xTiO_3$ thin films
photo-, thermal and humidity sensitivity characteristics of $Sr_{1-x}La_xTiO_3$ film on SiO_2/Si substrate, 223
Strain gages
shape optimal design and force sensitivity evaluation of six-axis force sensors, 105
Strain sensors
white-light interferometric fiber-optic distributed strain-sensing system, 177
Subtended angles
Faraday current sensors and the significance of subtended angles, 119

Temperature coefficient of resistance
electrical properties of nickel–zirconia cermet films for temperature- and flow-sensor applications, 33
Tetramethylammonium hydroxide (TMAH)
TMAH etching of silicon and the interaction of etching parameters, 243
Thermal conductivity detectors
fully integrated thermal conductivity sensor for gas chromatography without dead volume, 191
Thermal optimization
theoretical and experimental study of silicon micromachined microheater with dielectric stacked membranes, 183
Thermal sensitivity
photo-, thermal and humidity sensitivity characteristics of $Sr_{1-x}La_xTiO_3$ film on SiO_2/Si substrate, 223
Thin films
on the accuracy of the quartz-crystal microbalance (QCM) in thin-film depositions, 41
Tuning
tuning a bulk-glass optical current sensor by controlling conditions external to its reflecting surfaces, 27

Ultrasonic transducers
an integrated PVDF ultrasonic sensor with improved sensitivity using polyimide, 147

Vibration control
cantilever vibration control by electrostatic actuation for magnetic force microscopy, 125
Vibration-induced noise
analysis of the effect of vibration-induced noise in different fibre leads used in an optical current-measurement system, 113

White-light interferometry
white-light interferometric fiber-optic distributed strain-sensing system, 177
evaluation of different adaptive filtering techniques applied to white-light interferometric sensor systems, 197

Zinc oxide
the use of sputtered ZnO piezoelectric thin films as broad-band microactuators, 135
electrical characterization of sputter-deposited ZnO coatings on optical fibers, 153
Z-match technique
on the accuracy of the quartz-crystal microbalance (QCM) in thin-film depositions, 41